

ABSTRACT OF DISCLOSURE

The invention provides a semiconductor device that can inspect the connection states of power source terminals and grounding terminals of a test LSI at a low cost and in a short time, and an inspection method for the same. Switches SW1 to SW3 are provided between a plurality of power source terminals PD1 to PD3 and a power source line 10 inside the test LSI 4. A switch SWT is provided between the power source line and a grounding line 11 inside the test LSI. When inspecting the connection state of a certain power source terminal, the switch connected between the power source terminal and the power source line is closed, the switch SWT between the power source line and the grounding line is closed, and remaining switches are opened. A voltage is supplied between the power source terminal and a grounding terminal, and whether or not the power source terminal is in the connected state is determined by whether or not a current flows.

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